## Josephson current in ballistic N b/InA s/N b highly transm issive junctions

Francesco Giazotto, Kasper Grove-Rasmussen, Rosario Fazio, and Fabio Beltram NEST-INFM & Scuola Normale Superiore, I-56100 Pisa, Italy

> Edmund H. Lin eld and David A. Ritchie Cavendish Laboratory, University of Cambridge, Madingley Road, Cambridge CB3 OHE, United Kingdom

## Abstract

Highly transm issive ballistic junctions are demonstrated between Nb and the two-dimensional electron gas formed at an InAs/AlSb heterojunction. A reproducible fabrication protocol is presented yielding high critical supercurrent values. Current-voltage characteristics were measured down to 0.4 K and the observed supercurrent behavior was analyzed within a ballistic model in the clean limit. This investigation allows us to demonstrate an intrinsic interface transmissiv-ity approaching 90%. The reproducibility of the fabrication protocol makes it of interest for the experimental study of InAs-based superconductor-sem iconductor hybrid devices.

E lectronic address: giazotto@ sns.it

Superconductor-sem iconductor-superconductor (S-Sm -S) hybrid devices have been of considerable interest over recent years as a result of their potential for use in a signi cant number of applications [1]. Am ongst these the Josephson eld e ect transistor (JoFET) [2] is of particular technological relevance. Operation of the JoFET is based on the modulation of the Josephson coupling between two adjacent S contacts by the variation of the carrier density of the Sm layer separating them. In these hybrid structures supercurrent originates from current-carrying bound states [3] due to Andreev re ection [4]. The latter converts quasiparticle current in the sem iconductor into Cooper-pair current in the superconductor. Key issues to be addressed in order to make these devices of practical interest include high S-Sm interface transmissivity (as required for an e cient Andreev re ection) and fabrication schemes allowing inter-electrode distances (L) much smaller than the sem iconductor coherence length Sm (in fact critical supercurrent values decrease proportionally to  $e^{L = sm}$  [5]). Favorable L = sm ratios can be achieved by electron beam lithography (EBL), yielding a small electrode spacing, in combination with Sm layers consisting of high-quality two-dimensional electron gases (2DEGs). The latter provide electron mean free path  $m_{\mu}$ m obility and coherence-length values signi cantly exceeding those obtained in bulk sem iconductors. A more challenging issue is the fabrication of high-transm issivity S-Sm contacts. For G aA s-based 2D EG s the dom inant factor lim iting interface-transm issivity is represented by the presence of the Schottky barrier for which penetrating alloyed superconducting ohm ic contacts proved to be e ective in achieving good interface transparency [6]. This method, however, su ers from the poor geometric de nition intrinsic to the alloying process making it poorly compatible with high-resolution EBL. An e cient alternative is based on the exploitation of III-V sem iconductor alloys with high In content [7] and in particular on InA sbased 2DEGs [8]. These can provide Schottky barrier-free m etal-sem iconductor contacts. The residual transparency-lim iting factors are much less severe and stem from Ferm i-velocity m ism atch [9] and/or interface contam inants.

In this letter we report the fabrication and characterization of highly transmissive Nb/2DEG/Nb ballistic junctions made in the InAs/AlSb system. Current-voltage characteristics were measured down to 0.4 K and the observed supercurrent behavior was analyzed within a ballistic model in the clean limit. This investigation allows us to demonstrate an intrinsic interface transmissivity close to 90% in our system. The reproducibility of the fabrication protocolm akes it of interest for the experimental study of InAs-based S-Sm hybrid

2

devices.

The sem iconductor portion of the structure (sketched in Fig. 1 (a)) was grown by molecular beam epitaxy without intentional doping on a sem i-insulating G aA s(100) substrate. The Sm link consists of a 10-nm -wide InA s quantum well sandwiched between A ISb barriers. A 5 nm G aSb cap layer was grown on top of the structure in order to protect the A ISb layer from oxidation. Standard photolithographic techniques and wet etching [10] were used to de ne a 20-m -wide H all-bar m esa. At T = 0:3 K we measured a sheet electron concentration n ' 7:4 10<sup>1</sup> cm<sup>2</sup> and an electron mobility ' 75000 cm<sup>2</sup>/Vs. An elective m ass m = 0.036 m<sub>e</sub>, with m<sub>e</sub> the free electron m ass, was deduced from temperature-dependent Shubnikov-de H aas measurements. A nother useful parameter, the single-particle dephasing length ' was measured at T = 0:3 K by weak localization magnetoresistance measurements and a value of 2.7 m was obtained. These results allow us to calculate the electron mean free path 'm ' 1:1 m and a therm al coherence length in the clean limit sm (T) = hy = 2 k<sub>B</sub> T = 0:35 m /T, where v<sub>F</sub> is the Ferm i velocity in the InA s layer. For T 0.8 K, sm (T) < 'm, i.e. electron transport in the sample is in the clean limit.

S/2D EG /S junctions were patterned with a single EBL step. First, two 20- m-wide openings separated by a 190-nm-wide channel were de ned in a single PMMA layer (see Fig. 1 (b), (c)) and the G aSb/A ISb top layers were removed by wet etching in order to expose the InA s well. The sam ple was then baded into an UHV deposition chamber (background pressure of  $p = 1.2 \quad 10^{10}$  Torr) to carry out the S electrode deposition. Before performing the latter, the exposed areas were subjected to RF sputter-cleaning procedure [8]. The cleaning treatment was performed at p = 12 m Torr of Ar partial pressure, exposing the etched areas for 6 m inutes to a 0.3 W /cm<sup>2</sup> plasm a power density. Im mediately after this, 50-nm -thick Nb electrodes were deposited in situ by DC -m agnetron sputtering at a rate of about 30 A /s. The resulting Nb layer shows a critical tem perature  $T_c = 8.5$  K, corresponding to an energy gap = 1.4 m eV. The Nb/InA s-2D EG /Nb junctions were electrically characterized in a closed-cycle <sup>3</sup>He refrigerator from 0.4 K to tem peratures larger than  $T_c$  and current-driven four-term inal measurements were performed between the two Nb electrodes.

Figure 2 shows the current-voltage characteristics of a typical N b/InA s/N b junction in the 0.4 5.0 K tem perature range. The curves display a well-developed supercurrent I and no evidence of hysteresis was observed, as expected for overdam ped junctions [5]. At T = 0.4 K a 11 A critical supercurrent was measured corresponding to a critical-current linear density

of 0.55 A/m. To the best of our know ledge this value is an ong the highest reported for S/InA s-2D EG /S of comparable length and free-carrier concentration [8]. Furtherm ore, from the junction norm al-state resistance  $R_N = 15$ , a characteristic product  $I_c R_N = 165$  V is extracted which suggests good interface morphology [8]. The inset of F ig. 2 displays the current-voltage characteristic at T = 0.4 K over a wider bias range. The linear extrapolation of the curve from eV 2 to zero bias (dashed line in the inset) allow sus to determ ine the junction excess current,  $I_{exc}$  ' 57 A. This quantity is an inportant gure of merit in S-Sm – S weak links the magnitude of which strongly depends on interface quality. The excellence of this value can be understood by following the idealized one-dimensional S-N orm alm etal-S m odel in Ref. [11] which yields a rather high intrinsic barrier transparency Z 0.65 [12].

M one inform ation about the success of the fabrication protocol and on the properties of the hybrid system realized can be obtained by analyzing  $I_c$  as a function of tem perature in the tem perature range up to  $T_c$ . In fact this analysis allows us to determ ine some crucial junction parameters like the true interface transm issivity. Figure 3 (a) (full diam onds) shows the measured supercurrents normalized to the  $I_c$  value at T = 0.4 K as a function of the reduced tem perature  $(T=T_c)$ . The  $I_c$  (T) behavior follows a characteristic trend and  $I_c$ s decrease with increasing tem peratures [5]. For tem peratures lower than  $T=T_c$  0.1 data appear to saturate as expected for a non-perfectly transm issive S-Sm interface [13, 14]. A quantitative description of the data can be performed, but much care must be taken in carrying out this analysis ow ing to the two-dimensional nature of the InA's region, which is coupled to bulk Nb electrodes. Indeed supercurrent values may be deeply a ected by the abrupt dimensionality change at the S-Sm contact, by the change in electron electron electron matches.

As mentioned above, the electrode separation (L = 190 nm) favorably compares with  $r_m$  ( $r_m$  L) and allows a ballistic analysis of the system. This makes it possible to take advantage of them odel developed by Chrestin and co-workers [14]. These authors considered the S/2DEG/S structure sketched in the inset of Fig. 3(a). It consists of an InA s-2DEG of length L laterally contacted through identical potential barriers to two superconducting bulk leads. In our case of InA s-based weak links the contact transmissivity is limited by the Ferm i-velocity m ism atch between the S and the Sm layers and by contaminants at the interface resulting from the fabrication procedure. The in uence of the latter on interface transparency can be conveniently modeled by a function weighted by a dimensionless

4

parameter Z [15]. The norm al-state contact transm issivity T can be readily obtained from these two contributions as  $T = 4R [4R Z^2 + (1 + R)^2]^1$  [9], where R is the ratio of the Fermi velocities between S and Sm. Solving the Bogolubov-de Gennes equations, the Josephson current in the system can be calculated as a function of the structure parameters. The tem perature dependence of the critical current  $I_{\rm c}$  (T) can also be obtained and compared with our experiment. Figure 3(a) (open circles) shows the best to the data computed with the model described above. It was calculated employing the parameters for InAs and Nb determ ined experimentally with a single thing parameter: a barrier strength Z = 0.4[17]. The experimental data are well described by this model over the whole temperature range thus further supporting our description of the system in the clean limit. The tted value Z = 0:4 translates into an intrinsic barrier transm issivity exceeding 86% and in a total contact transm issivity of the order of 80% (including the existing Nb/InAs Ferm i-velocity m ism atch). This very large value is consistent with the di erential-conductance versus bias (G (V)) behavior in the 4:6 8:5 K tem perature range (see Fig. 3(b)). (In this tem perature range the supercurrent was not measurable.) The curves show a large enhancem ent for energies lower than 2 = e and a peculiar reproducible structure is visible within this energy range on the G (V) spectra. The non monotonic behavior observed can be ascribed to multiple Andreev re ections o the Nb electrodes [11]. The resulting resonances are too weak to allow a detailed comparison with the theory, but this very fact is fully consistent with the highly transmissive nature of S-Sm contacts as theoretically predicted in Ref. [11].

In sum m ary, N b/InA s-2D EG /N b ballistic weak links were fabricated and characterized as a function of tem perature. The devices shows a supercurrent of 11 A at T = 0.4 K and a good value for the product  $I_cR_N = 165$  V.A theoretical model in the clean limit describes well the experimental behavior of these structures and allow s us to estimate a high value for the intrinsic contact transmissivity approaching 90%. Our results were made possible by the fabrication procedure adopted here and suggest that the N b/InA s-2D EG combination m ay be considered as the prototype system on which to implement successfully high-performance Josephson-type devices.

The authors would like to acknow ledge P.P ingue for fruitful discussions. This work was supported by INFM under the PAIS projects EISS and TIN, and by EPSRC (UK). EHL

adknow ledges support from Toshiba Research Europe Ltd.

- [1] A W K leinsasser and W .L.G allagher, Superconducting D evices, edited by S.Ruggero and D.
  Rudman (A cademic, Boston, 1990), p. 325.
- [2] T.Akazakiet al., Appl. Phys. Lett. 68, 418 (1996).
- [3] I.O.Kulik, Sov.Phys.JETP 57, 1745 (1969).
- [4] A.F.Andreev, Zh.Eksp.Teor.Fiz. 46, 1823 (1964).
- [5] K.K.Likharev, Rev.M od.Phys.51, 101 (1979).
- [6] A.M. Marsh et al, Phys. Rev. B 50, 8118 (1994); K.M. Lennsen et al., ibid. 63, 2079 (1993).
- [7] A.W. Kleinsasser et al, Appl. Phys. Lett. 55, 1909 (1989); Th. Schapers et al, ibid. 71, 3575 (1997).
- [8] C.Nguyen et al., Appl. Phys. Lett. 57, 87 (1990); A.Chrestin and U.Merkt, ibid. 70, 3149 (1997); G.Bastian et al., ibid. 75, 94 (1999); J.N itta et al., Phys. Rev. B 46, 14286 (1992); J.P.Heida et al., ibid. 60, 13135 (1999); L.C.Muret al., ibid. 54, R2327 (1996).
- [9] G.E.Blonder and M.Tinkham, Phys. Rev. B 27, 112 (1983).
- [10] We employed a NH<sub>4</sub>OH (25%) DI water (1:5), 60 ml solution to etch the GaSb and AlSb layers, while for the InAs layer we used a CH<sub>3</sub>COOH (99%) H<sub>2</sub>O<sub>2</sub> (30%) DI water (1:5:1), 60 ml solution.
- [11] M.Octavio et al, Phys. Rev. B 27, 6739 (1983); K.Flensberg et al, ibid. 38, 8707 (1988).
- [12] The Z value stems from the known overestimation of barrier reactivity in such idealized models. See Ref. 16.
- [13] U.Schussler and R.Kummel, Phys.Rev.B 47, 2754 (1993).
- [14] A. Chrestin et al, Phys. Rev. B 49, 1391 (1994).
- [15] G.E.Blonder et al, Phys. Rev. B 25, 4515 (1982).
- [16] N.A.M ortensen et al, Phys. Rev. B 59, 10176 (1999).
- [17] An electrode separation  $L_{eff} = L + 2L_t$  was employed in the thing procedure. As pointed out in Ref. [5] this is consistent with a coplanar geometry like the present one. The transfer length, i.e., the InAs portion under each Nb contact actively participating to the transport,  $L_t = 280$  nm, was independently measured by transfer length method (TLM) measurements on separate test structures.

FIG.1: (a) Sketch of the Nb/InAs-2DEG/Nb m icrostructure. The Nb-electrode separation is L = 190 nm. (b) Scanning electron m icrograph of the device. The mesa lateral arm s were used as additional probes for electrical characterization. (c) M agni ed view of Fig. 1 (b) showing the sem iconductor channel separating the two Nb contacts.

FIG. 2: Current-voltage characteristics of the Nb/InAs/Nb weak link in the 0:4 5 K temperature range. Curves are horizontally o set for clarity. From left to right, data were taken at T = 0:4; 1:0; 1:9; 2:0; 2:5; 2:8; 3:1; 3:6; 4:0; 4:5; and 5:0 K. The inset shows the current-voltage characteristic measured at T = 0:4 K over a wider bias range. The linear extrapolation to V = 0yields an excess current of 57 A.

FIG. 3: (a) Temperature dependence of the normalized critical current (full diamonds). The theoretical calculation (open circles) follows from the model of Ref. [14] with Z = 0.4 (the model structure is sketched in the inset, see text). (b) D i erential conductance vs. voltage for several temperature values. The weak but reproducible structure superimposed on the curves can be ascribed to multiple Andreev rejections (see text).

This figure "Fig1bis.jpg" is available in "jpg" format from:

http://arxiv.org/ps/cond-mat/0207337v1

This figure "Fig2bis.png" is available in "png" format from:

http://arxiv.org/ps/cond-mat/0207337v1

This figure "Fig3bis.png" is available in "png" format from:

http://arxiv.org/ps/cond-mat/0207337v1